

ABSTRACT**FABRICATION OF FABRY-PEROT POLYMER FILM SENSING
INTERFEROMETERS**

A method of forming an interferometer film for an interferometer sensor comprises forming a parylene polymer layer (8) of substantially uniform thickness directly on an interferometer substrate (4;45), the layer forming the interferometer film. Since the interferometer film (8) is formed directly onto the surface of the interferometer substrate, there is improved conformity between the two surfaces at the interface between the polymer layer and the substrate and improved uniformity in the thickness of the film.

[Figure 1]